

ABSTRACT

A substrate processing apparatus capable of optimizing a measurement process
5 is disclosed. The substrate processing apparatus includes a load/unload unit arranging
load ports side by side adjacent to a front outer wall of a housing, and an upper
measurement module and a lower measurement module configured to measure a surface
condition of a substrate, and disposed side by side vertically adjacent to a side outer wall
of the housing connected to the front outer wall.

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FIG. 4